Abstract

In an apparatus (1) for processing substrates (2) in a liquid container (3) with a substrate receiving device (4, 68, 88) that can be placed over the liquid container (3) and has at least one pair of lateral guide elements (35, 36; 55, 56; 75, 76), substrates (2) having different dimensions can be received in that the guide elements (35,36; 55, 56; 75, 76) can be moved relative to one another.

(Fig. 1)

Note: All 4 paragraphs relating to the Japanese documents are to be deleted from the priority document translation